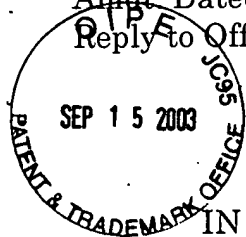


Appl. No. 09/291,538
Amdt Dated September 10, 2003
Reply to Office Action of March 10, 2003

Attorney Docket No. 005586/D8326 (81784.0208)
Customer No. 26021



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
Hidenori OGATA et al.
Serial No: 09/291,538
Confirmation No.: 2245
Filed: April 14, 1999
For: LASER ANNEAL METHOD OF A
SEMICONDUCTOR LAYER

Art Unit: 2822

Examiner: M.A. Wilczewski

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September 10, 2003

Date of Deposit

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Name

John P. Scherlach

Signature

Date

AMENDMENT

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In conjunction with the filing of the accompany Request For Continued Examination (RCE), and in response to the final Office Action of March 10, 2003, the period for response to which is being extended by 3-months to September 10, 2003 by the accompanying petition, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the Listing of Claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.

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